## 504536577 09/07/2017

# PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1 Stylesheet Version v1.2 EPAS ID: PAT4583284

SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

### **CONVEYING PARTY DATA**

Name	Execution Date
KAZUKI ISHIZAWA	07/28/2017
HIROYUKI CHIBA	07/28/2017
YOSHIHIRO TAKAHOKO	07/28/2017
DAICHI NARA	08/01/2017

### **RECEIVING PARTY DATA**

Name:	HITACHI HIGH-TECHNOLOGIES CORPORATION	
Street Address: 24-14, NISHI SHIMBASHI 1-CHOME		
City: MINATO-KU, TOKYO		
State/Country:	JAPAN	

### **PROPERTY NUMBERS Total: 1**

Property Type	Number
Application Number:	15556400

### **CORRESPONDENCE DATA**

**Fax Number:** (202)628-8844

Correspondence will be sent to the e-mail address first; if that is unsuccessful, it will be sent

using a fax number, if provided; if that is unsuccessful, it will be sent via US Mail.

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Email: lbuckler@crowell.com

Correspondent Name: CROWELL & MORING LLP

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Address Line 4: WASHINGTON, D.C. 20004

ATTORNEY DOCKET NUMBER:	104349.PA310US
NAME OF SUBMITTER:	MICHAEL H. JACOBS
SIGNATURE:	/Michael H. Jacobs/
DATE SIGNED:	09/07/2017

### **Total Attachments: 4**

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> PATENT REEL: 043521 FRAME: 0498

## **ASSIGNMENT**

(譲渡証)

As a below named inventor, I hereby declare that:

IN CONSIDERATION of the sum of One Dollar (\$1.00) or the equivalent thereof, and other good and valuable consideration paid to me citizen of Japan by HITACHI HIGH-TECHNOLOGIES CORPORATION, a corporation organized under the laws of Japan,

located at 24-14, Nishi Shimbashi 1-chome, Minato-ku, Tokyo, Japan, receipt of which is hereby acknowledged I do hereby sell and assign to said

HITACHI HIGH-TECHNOLOGIES CORPORATION,

its successors and assigns, all my right, title and interest, in and for the United States of America, in and to

# CHARGED PARTICLE BEAM APPARATUS, ALIGNMENT METHOD OF CHARGED PARTICLE BEAM APPARATUS, ALIGNMENT PROGRAM, AND STORAGE MEDIUM

invented by me (if only one is named below) or us (if plural inventors are named below) and described in the application for United States Letters Patent therefor, No. PCT/JP2015/060098 filed March 31, 2015, and all United States Letters Patent which may be granted therefor, and all divisions, continuations and extensions thereof, the said interest being the entire ownership of the said Letters Patent when granted,

to be held and enjoyed by said. HITACHI HIGH-TECHNOLOGIES CORPORATION,

its successors, assigns or other legal representatives, to the full end of term for which said Letters Patent may be granted as fully and entirely as the same would have been held and enjoyed by me or us if this assignment and sale had not been made:

And I hereby agree to sign and execute any further documents or instruments which may be necessary, lawful, and proper in the prosecution of the above-named application or in the preparation and prosecution of any continuing, continuation-in-part, substitute, divisional, renewal, reviewed or reissue applications or in any amendment, extension, or interference proceedings, or otherwise to secure the title thereto in said assignee;

And I do hereby authorize and request the Commissioner of Patents to issue said Letters Patent to said HITACHI HIGH-TECHNOLOGIES CORPORATION,

Signed on the date(s) indicated aside our signatures:

Date Signed (署名日)	INVENTOR(S) (発明者フルネームサイン)			
7/28/2017	Kazuki ISHIZAWA	deligour.	formi	1)
	Hiroyuki CHIBA			2)_
	Yoshihiro TAKAHOKO			3)
	Daichi NARA			4)

PATENT REEL: 043521 FRAME: 0499

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Signed on the date(s) indicated aside our signatures:

15 15 15 CO C (O)

	inventor(s) (発明者フルネームサイン)	Date Signed (署名日)
1)	Kazuki ISHIZAWA	
2)	Hiroyuki Chiba Hiroyuki CHIBA	7/28/2017
3)	Yoshihiro TAKAHOKO	
4)	Daichi <b>N</b> ARA	

PATENT REEL: 043521 FRAME: 0500

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Signed on the date(s) indicated aside our signatures:

INVENTOR(S)

(発明者フルネームサイン)		(署名日)	
1)_	Kazúki ISHIZAWA	-	
2)_	Hiroyuki CHIBA		
.3)	Yoshihiro Takahoko Yoshihiro TAKAHOKO	7/28/2017	
4)	Daichi NARA		

PATENT REEL: 043521 FRAME: 0501

Date Signed

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	(発明者フルネームサイン)	.uate Signist (署名日)	
1)	Kazuki (SHIZAWA		
2)_	Hiroyaki CHIBA		
3)	Yoshihiro TAKAHOKO		
4)	Daichi NARA Daichi NARA	August 1, 2017	

PATENT REEL: 043521 FRAME: 0502

RECORDED: 09/07/2017